

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Hiroyasu MATSUGAI, et al.**

Serial Number: **Not Yet Assigned**

Filed: **August 4, 2003**

For: **ORGANIC INSULATING FILM FORMING METHOD, SEMICONDUCTOR DEVICE
MANUFACTURE METHOD, AND TFT SUBSTRATE MANUFACTURE METHOD**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 4, 2003

Sir:

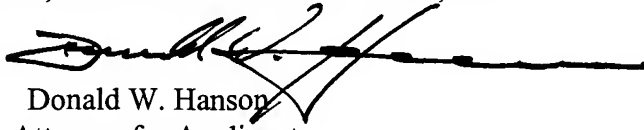
In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references, except for the U.S. patent reference, is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 01-2340.

Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO-1449; References (1)

INFORMATION DISCLOSURE STATEMENT PTO-1449	Atty. Docket No. 030861	Serial No. New Application
	Applicant(s): Hiroyasu MATSUGAI, et al.	
	Filing Date: August 4, 2003	Group Art Unit: Not Yet Assigned

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA	4,756,977	L. Haluska et al.	07/12/88			
_____	AB						
_____	AC						
_____	AD						

FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Translation (Yes or No)
_____	AE	63-144525	06/16/88	Japan	No-Discussed in the specification
_____	AF				
_____	AG				
_____	AH				
_____	AI				

OTHER DOCUMENTS

_____	AJ	
_____	AK	
Examiner		Date Considered